

Title (en)

RECESSED COIL FOR GENERATING A PLASMA

Title (de)

VERSENKTE SPULE ZUR PLASMAERZEUGUNG

Title (fr)

BOBINAGE A EVIDEMENT SERVANT A GENERER UN PLASMA

Publication

EP 0845151 A1 19980603 (EN)

Application

EP 97925528 A 19970508

Priority

- US 9708008 W 19970508
- US 64718296 A 19960509

Abstract (en)

[origin: WO9742648A1] A recessed coil for a plasma chamber in a semiconductor fabrication system is provided. Recessing the coil reduces deposition of material onto the coil which in turn leads to a reduction in particulate matter shed by the coil onto the workpiece.

IPC 1-7

H01J 37/32; H01J 37/34

IPC 8 full level

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CPC (source: EP KR)

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Citation (search report)

See references of WO 9742648A1

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